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INFORMATION DISCLOSURE STATEMENT PTO-1449	Atty. Docket No. 030757	Serial No. New Application
	Applicant(s): Akihiko OTOGURO, et al.	
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U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA					
_____	AB					
_____	AC					
_____	AD					

FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Translation (Yes or No)	
<u>CK</u>	AE	4-5658	01/09/92	Japan	Yes-Abstract/Discussed in the specification
<u>CK</u>	AF	60-254034	12/14/85	Japan	Yes-Abstract/Discussed in the specification
<u>CK</u>	AG	5-265224	10/15/93	Japan	Yes-Abstract/Discussed in the specification
_____	AH				
_____	AI				

OTHER DOCUMENTS

<u>CK</u>	AJ	J.M. Moran et al.; "High resolution, steep profile resist patterns"; <i>Journal of Vacuum Science Technology</i> ; Vol. 16; No. 6; November/December 1979; pp. 1620-1624./Discussed in the specification.
_____	AK	

Examiner <u>Christy Horacek</u>	Date Considered <u>7/8/04</u>
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